



Discontinuous cracking of TiN film induced by adhesive interlayer under tension

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4 **Discontinuous cracking of TiN films on a steel substrate induced by an adhesive**
5
6 **interlayer**
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35 **Abstract**

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37 The basic mechanisms governing the process of cracking of single-layer brittle
38 films have been extensively explored through both simulations and experiments.
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40 However, the role that an adhesive interlayer plays in the cracking of the overlying
41 brittle film remains unclear. By performing three-point bending experiments, we
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43 observed that the insertion of a 100 nm thick Ti interlayer changed the cracking
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45 behavior of TiN films from a continuous pattern to a discontinuous pattern. The slight
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47 change in the microstructure of the film and the increase in film thickness arising from
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49 the addition of the Ti interlayer are unlikely to cause the observed cracking morphology.
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4 The combination of the different interface between the Ti and the steel substrate and
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6 the fracture of the Ti interlayer are responsible for the transition in the TiN film cracking
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8 morphologies.
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14 *Keywords:* TiN film; Ti interlayer; cracking morphology transition; interfaces;
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16 interlayer fracture.
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18 19 20 21 22 **1. Introduction**

23
24 Brittle films prepared by magnetron sputtering are one of the most common surface
25
26 modification methods for preventing damage to the underlying substrates without
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28 changing their surface components and structure [1]. However, the brittle films
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30 produced by this technique usually exhibit large residual compressive stress and poor
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32 adhesion, which results in film interfacial delamination [2-5]. A metallic interlayer,
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34 such as Cr, Ta or Ti, is usually applied to solve such problems [6-12]. Previous studies
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36 have reported that the insertion of such interlayers can significantly affect the cracking
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38 behavior of ductile Cu films [6, 8, 12, 13], even causing these films to undergo a ductile-
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40 to-brittle transition [8]. However, the effects of an adhesive interlayer on the cracking
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42 behavior of brittle films have received relatively little attention.
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51 Generally, the cracking behavior of single-layer brittle films on ductile substrates
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53 under tension can be understood by a shear lag model, in which the normal stress in the
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55 substrate is transferred to the coating via a shear stress through the interface [7, 14-18].
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57 The presence of a brittle interlayer will transfer the stress from the substrate to the film
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4 and change the microstructure and properties of the film, thereby affecting its cracking
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6 behavior [19-21]. The aim of the present study is to explore how the interlayer affects
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8 the cracking process of the overlying brittle film.
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12 TiN films were prepared via magnetron sputtering on 50CrVA spring-steel
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14 substrates with or without a 100 nm Ti interlayer. The cracking behavior of sandwich
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16 specimens was studied using a homemade three-point bending device. The effect of the
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18 100 nm thick Ti interlayer on the cracking behavior of the TiN film is here evaluated
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20 and relevant mechanisms proposed.
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27 **2. Experimental procedures**

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30 The dimensions of the 50CrVA spring-steel substrates were 15.5 mm × 0.9 mm ×
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32 6 mm. The TiN films were deposited on either the front 15.5 mm × 0.9 mm surface (the
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34 lateral surface) to study the cracking behavior or the 15.5 mm × 6 mm surface (the top
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36 surface) to evaluate the residual stress. Two sets of approximately 1 μm thick TiN films
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38 were deposited on substrates with and without a 100 nm thick Ti interlayer, as shown
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40 in Fig. 1. Both TiN films exhibit a fine columnar structure and the addition of a Ti
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42 interlayer increases the columnar width of the films. To consume the residual oxygen
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44 and nitrogen in the chamber, the Ti target was pre-sputtered for 10 min with the
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46 substrate sheltered prior to film deposition. The TiN films were deposited using the
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48 same parameters as those used in previous studies [22, 23]. The Ti interlayer was
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50 deposited using reactive RF-pulsed magnetron sputtering with a 2×10^{-3} Pa base
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52 pressure, a 300 W target power, a 0.3 Pa deposition pressure and a 0.25 Pa Ar pressure.
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4 During the sputter deposition of the Ti interlayer, a bias of -80 V was applied to the
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6 substrate. In addition, Si substrates (20 mm × 20 mm) were also used to study the effect
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8 of the Ti interlayer on the cross-sectional microstructures of the TiN films.
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11 The cross-sectional microstructures of the TiN films with and without Ti
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13 interlayers were first characterized by scanning electron microscopy (SEM). The
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15 residual stresses in the films were determined with the XRD $\sin^2\psi$ method [19] and
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17 determined to be approximately -2.1 ± 0.5 GPa and -3.1 ± 0.9 GPa with and without a
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19 Ti interlayer, respectively. The TiN films deposited on the lateral surface were bent to
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21 a maximum strain of 6% at a strain rate of $2 \times 10^{-2} \text{ s}^{-1}$, similar to the approach used in
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23 our previous studies [22, 23].
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33 **3. Experimental results**

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35 The crack density of the TiN films after bending was measured along the
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37 longitudinal direction, as shown schematically in Fig. 2a. The maximum strain on the
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39 top surface of the sample was measured with a strain gauge. Assuming that the
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41 externally applied moment is constant along the same longitude, the strain can be
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43 calculated as follows:
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$$\varepsilon_x = \left(1 - \frac{2y}{h}\right) \varepsilon_{\text{top}} \quad (1)$$

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49 where h is the substrate thickness and y is the distance from the upper edge. Based on
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51 Eq. (1), the strain at the sites observed under SEM can be obtained by inserting the
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53 distance to the edge. Fig. 2b shows that the crack spacing of the TiN films decreases
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55 markedly at low strain and then gradually saturates when the films are bent to the
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4 maximum strain of 6%. The insertion of the Ti interlayer not only decreases the
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6 saturated crack spacing ($L_{\text{without}} \approx 7.7 \mu\text{m}$ and $L_{\text{with}} \approx 4.4 \mu\text{m}$) in the TiN film but also
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8 lowers the critical fracture strain ($\varepsilon_{\text{without}}=1.6\%$ and $\varepsilon_{\text{with}}=0.8\%$).
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11 Fig. 3 shows SEM images of the lateral surface of the TiN films deformed at a
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13 maximum strain of 6%. The cracks in the TiN film without a Ti interlayer are straight
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15 and continuous, whereas those with a Ti interlayer are discontinuous. The same
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17 phenomenon is also observed in both crack-initiation and crack-saturation stages. As
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19 previously mentioned, the normal stress in the substrate is transferred to the coating by
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21 the interface, meaning that the normal stress is transferred through the interlayer in this
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23 bilayer system. Therefore, the cracking morphology of a bare 100 nm Ti film (keeping
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25 the same deposition time as that used for the Ti interlayer) on the 50CrVA spring steel
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27 substrate was studied. Fig. 4a shows that the Ti layer forms many discontinuous and
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29 irregular cracks with a much smaller saturated crack spacing of $L \approx 0.33 \mu\text{m}$. Of
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31 particular interest, the critical strain for crack initiation in the Ti layer is approximately
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33 2.7%, which is much larger than that for the TiN films, as shown in Fig. 4b.
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46 **4. Discussion**

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48 The experimental results presented above reveal that the presence of the Ti
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50 interlayer produced three effects on the cracking behavior of the overlying TiN films
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52 (i.e. the Ti interlayer): decreasing the critical fracture strain, shortening the saturated
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54 crack spacing, and altering the cracking morphology. The first two effects can be
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56 attributed to the relief of compressive stress in the TiN films with a Ti interlayer, which
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4 will accelerate the crack initiation and subsequently decrease the saturated crack
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6 spacing of the films [23] according to the shear lag model [14]. In the following section,
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8 we will focus on the discussion of how the Ti interlayer affects the cracking
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10 morphology of the TiN films.
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14 The microstructure [25, 26], thickness [4, 27], and interfacial structure [28] of the
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16 films were reported to be able to alter the cracking morphologies of single brittle layers.
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18 For example, cracks in a crystalline $\text{Ge}_2\text{Sb}_2\text{Te}_5$ (GST) film deviated from straight paths
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20 as they propagated along the grain boundaries, whereas this phenomenon is not
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22 observed for cracks propagating in amorphous GST films [26]. A Cr film with columnar
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24 grains exhibits a network-type cracking with cracks regularly deviating from the
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26 direction perpendicular to the applied strain, whereas the cracks in a Cr film with
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28 equiaxed grains are straight [25]. In polyimide-supported Cr films, the cracking
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30 morphology transforms from network-type to straight cracking as the film thickness
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32 increases from 50 nm to 150 nm [4]. However, polyimide-supported Ti films exhibit
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34 straight cracks in thinner 8 nm films, whereas these films exhibit zig-zag cracks for
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36 thicker 50 nm films [27]. In addition, the change in interfacial structures also affects
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38 the film cracking morphologies. For instance, the annealing-induced crystallization of
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40 the amorphous interlayer at the interface changes the film morphology from zig-zag
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42 cracking to straight cracking [27]. Herein, the effects of the microstructure, thickness
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44 and interfacial structure of the films on the resultant cracking morphologies are
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46 individually considered.
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58 Fig. 1 shows that the presence of a Ti interlayer simply increases the columnar width,
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4 and there are no essential differences in the microstructures of the two sets of TiN films.
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6 In addition, the cracking morphology of the 1.1 μm thick TiN without Ti interlayer is
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8 straight and continuous, as shown in Fig. 5. Therefore, the changes in the
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10 microstructures of the TiN films and the increase in the film system thickness arising
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12 from the addition of a Ti interlayer are unlikely to cause the cracking morphology to
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14 transform in the present study. The influence of the Ti interlayer on the cracking of the
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16 TiN film can be divided into two steps with respect to the applied strain. When the
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18 applied strain is less than 2.7% (the critical strain of the Ti layer), the normal stress in
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20 the substrate transferred to the film and the resultant cracking are mainly controlled by
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22 the Ti/steel interface. Fig. 4a shows that the normal stress transferred from the substrate
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24 through this interface, causing discontinuous and irregular cracking in the Ti film.
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26 Therefore, we attribute the discontinuous cracking of the TiN film at the crack initiation
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28 stage to different stress transfers through the Ti/steel interface, as shown in Fig. 3d.
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38 Once the Ti interlayer fractures (the applied strain exceeds 2.7%), the cracking
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40 process of the overlying TiN film will be subjected to two effects. The first is tensile
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42 stress relief, which reduces the stress transfer to the overlying TiN film; hence, a higher
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44 strain is required for further cracking [15]. In addition, the formation of cracks also
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46 causes stress redistribution in the uncracked Ti segments [12, 15], thereby affecting the
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48 stress transfer to the TiN film. The other effect is a stress concentration generated in the
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50 TiN film above the Ti interlayer; this stress concentration is located near the cracks in
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52 the Ti layer [12]. As the applied strain increases, an increasing amount of stress
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54 transfers to the TiN film through the uncracked Ti segment, and the stress concentration
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4 becomes more substantial due to the increased crack opening of the Ti interlayer, which
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6 will eventually cause the TiN film to fracture. The above discussions indicate that the
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8 cracking process of the TiN film is highly dependent on the fracture of the Ti interlayer.
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10 The discontinuous cracking of the TiN film will be promoted once the underlying Ti
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12 interlayer fractures. In addition, as indicated in Figs. 2b and 4b, the saturated cracking
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14 spacing of the Ti film is much smaller than that of the TiN film; therefore, the cracking
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16 of the Ti interlayer also contributes to decreasing the saturated crack spacing of the TiN
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18 film.
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28 **5. Conclusions**

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30 In the present study, the influence of a 100 nm thick Ti interlayer on the cracking
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32 behavior of a 1 μm TiN film adhered to a Si substrate was experimentally investigated.
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34 The results showed that the Ti interlayer contributed to an increase in the columnar
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36 width and a relief of the compressive stress. In three-point bending tests, the cracking
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38 morphology of the TiN films changed from a continuous pattern to a discontinuous
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40 pattern due to the presence of the Ti interlayer. The slight change in the microstructure
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42 of the TiN film and the increase in film thickness due to the addition of Ti interlayer
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44 were unlikely to cause the cracking morphologies to transform. The different interface
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46 between the Ti and the steel substrate and the cracking of the Ti interlayer are attributed
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48 to altering the stress transfer across the interface to the TiN film, leading to the resultant
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50 transition in cracking morphology. The relief of compressive stress and the cracking of
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52 the Ti interlayer created a stress concentration that decreased the saturated cracking
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spacing of the TiN film.

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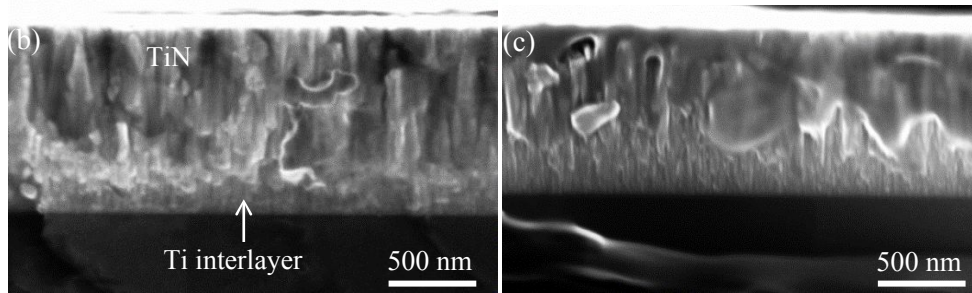


Fig. 1. The SEM cross-sectional microstructures of TiN films: (a) with Ti interlayer;

(b) without Ti interlayer

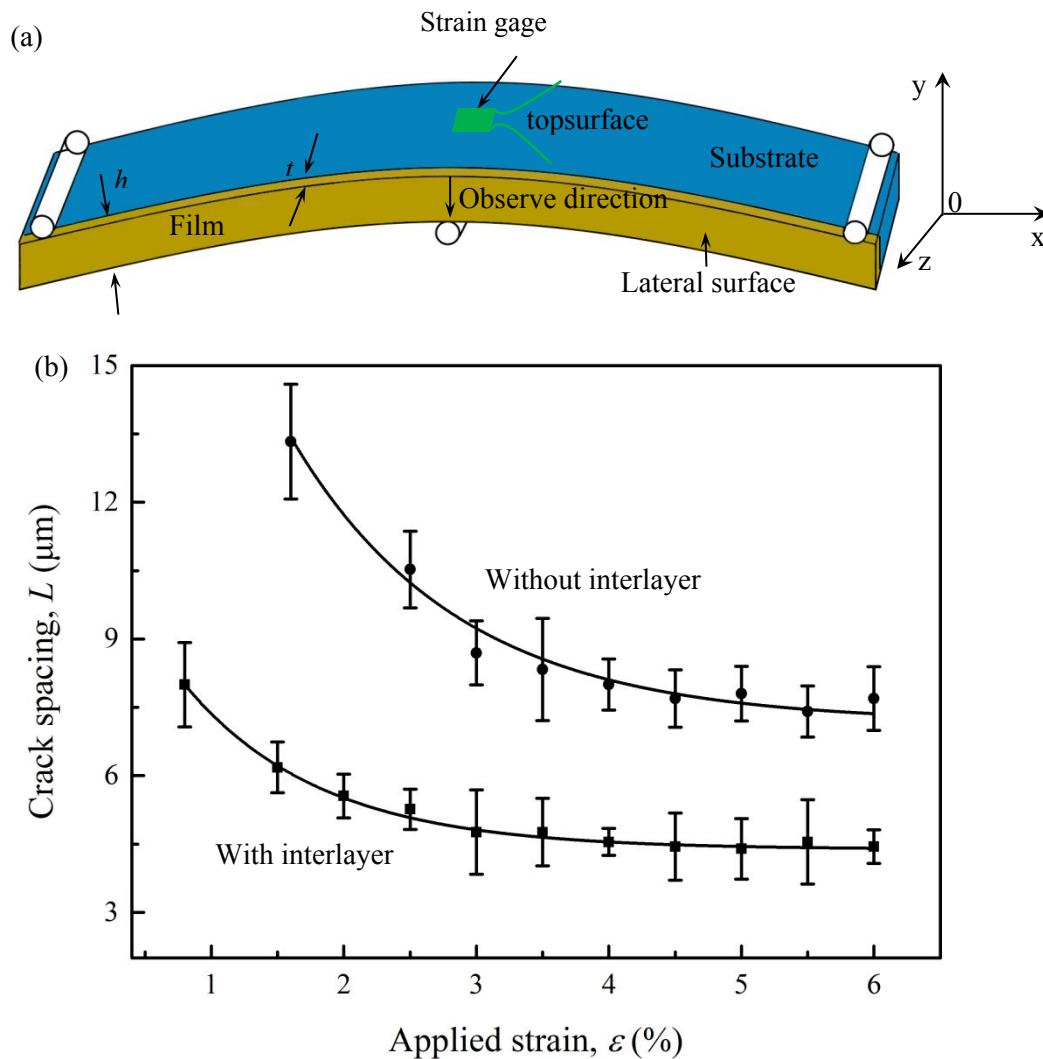


Fig. 2 (a) Schematics of the sample in three-point bending. The film is on the lateral surface, labelled by yellow color. (b) Crack spacing as a function of the applied tensile strain for TiN film with and without Ti interlayer under three-point bending.

Three specimens were used for each point.

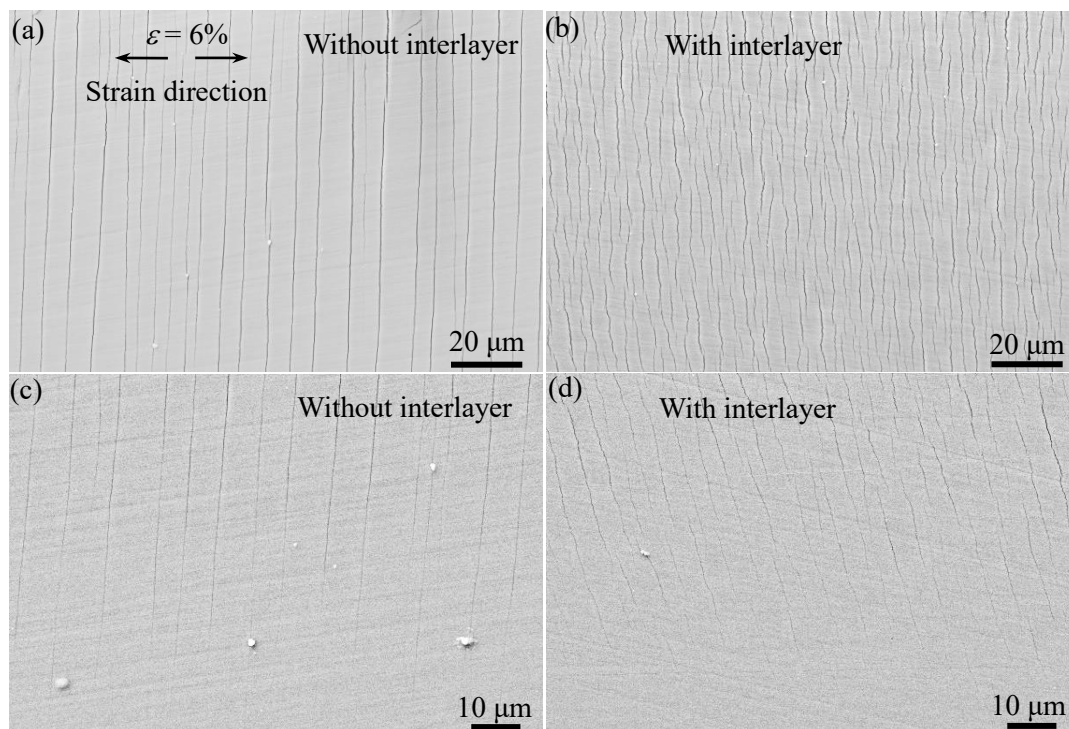


Fig. 3. SEM micrographs of TiN films (about 1 μm) strained to approximately 6% under three-point bending: (a) and (c) without Ti interlayer showing straight and continuous cracks, (b) and (d) with Ti interlayer showing discontinuous cracks. (a) and (b) are micrographs at the strain of 6%, (c) and (d) are micrographs when the cracks start to appear.

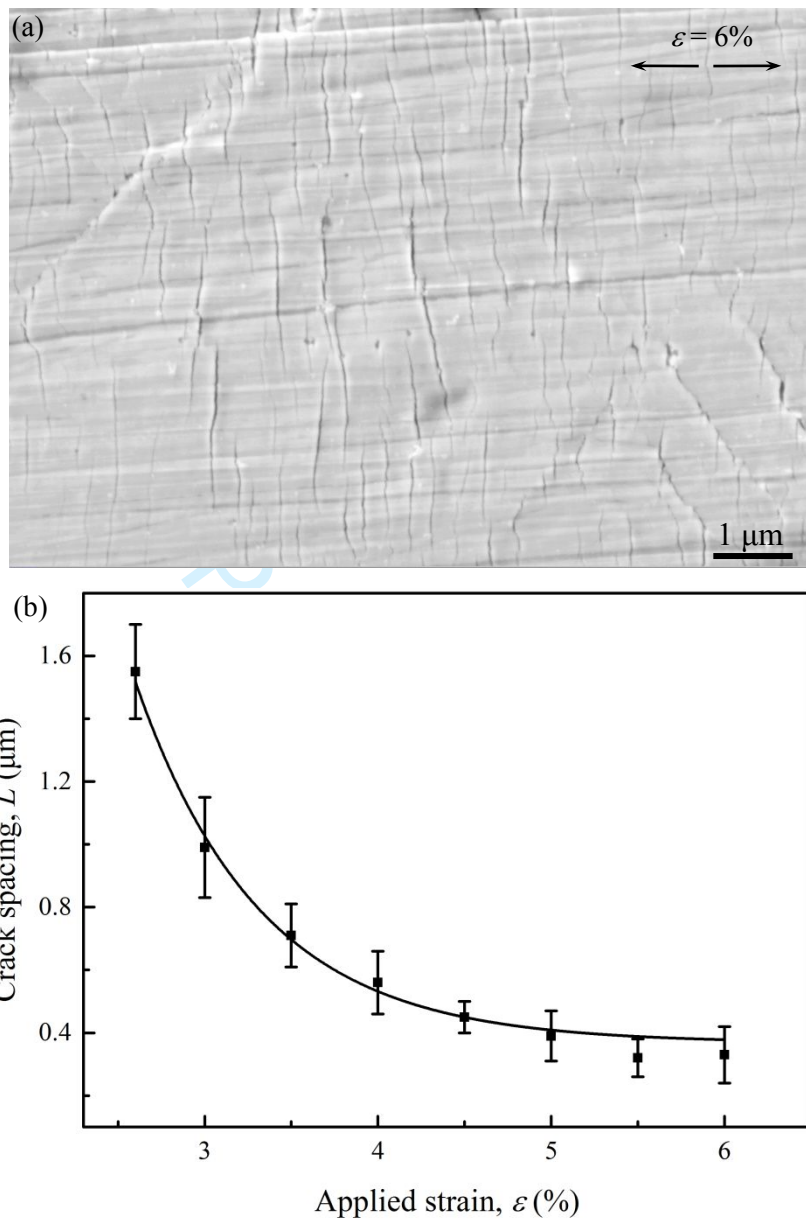


Fig. 4. (a) SEM micrograph of bare 100 nm Ti film surface strained to approximately 6% under three-point bending. (b) Crack spacing as a function of the applied tensile strain.

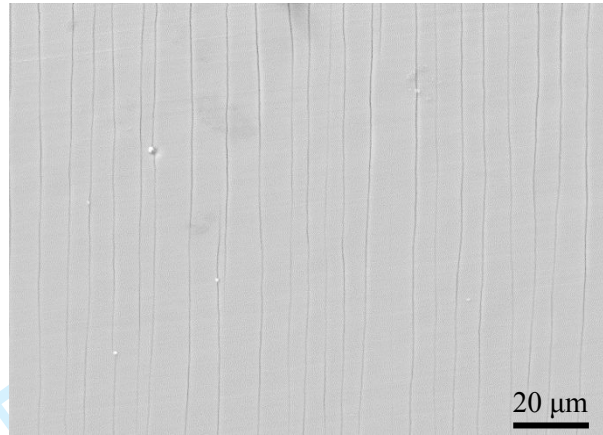


Fig. 5 SEM micrograph of TiN film (about 1.1 μm) strained to approximately 6% under three-point bending, showing straight and continuous cracks.